

JETLIGHT

BATCH TYPE

RAPID THERMAL

PROCESS FURNACE



ECM Technologies' JetLight is the entry-level, desktop controlled furnace for ECM Lab Solutions. It is a compact and yet robust, high speed heat treatment system with a wide range of material substrates for rapid thermal annealing (RTA). The furnace is equipped with a tubular quartz reaction chamber, and the lamp array, upper flange, and quartz window are mounted in a rotating top lid, which gives full access to the chamber for easy wafer loading and unloading. Silicon carbide coated graphite susceptors are available for various small sample and compound semi materials processing. A PID system also provides accurate and repeatable thermal control across the temperature range. The high reliability and performance characteristics allow for small-scale production. These make the JetLight system ideal for meeting the needs of universities and research centers looking for RTP systems in a multi-user environment.



SUBSTRATE SIZE

2-inch diameter (up to 50 mm diameter) and Maximum length of 150 mm

- SEMI
- Optoelectronic
- Microelectronics
- MEMS
- PV

AN ECM GROUP OFFER

ECM Lab Solutions helps laboratories to develop innovative products and processes by offering advanced furnace technologies under one ECM Group brand. This offer gathers all laboratory furnaces from the ECM Group. Its expertise includes the heat treatment of steels, ceramics and silicon. As well as crystal growth applications, coatings and melting processes for a wide range of research fields.



FEATURES

Reactor technology

Water cooled metal chamber

RTP heating system

Crossed-lamp IR Technology

Temperature range

RT to 1000°C

Temperature uniformity (typical)

±1°C

Ramp rate

1°C/s to 200°C/s

Temperature control

TCs, Pyrometer & digital PID

Cooling

Fan & water-cooled reflector

Process

Atmospheric pressure or under vacuum

APPLICATIONS

Rapid thermal process (RTP)

RTA - RTO - RTN

Crystallization

Densification



OPTIONS

- Primary vacuum, pump
- Susceptor
- Software-controlled stand-alone single chamber reactor
- Hot wall chamber design
- Microprocessor-controlled, thyristor technology
- Up to 2 MFC , controlled gas introduction lines
- Atmospheric and vacuum process capabilities
- PID temperature control through thermocouples

RTP FURNACES RANGE



JETSTAR

Standalone RTP Furnace



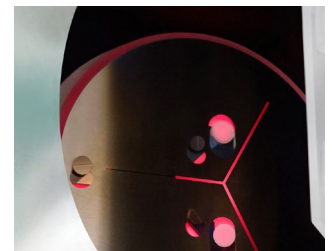
JETCLIP

SEMI - MESC RTP Module



JETFIRST

Bench Top RTP Furnace



ECM TECHNOLOGIES

Tel. : +33 (0)4 76 49 65 60
info@ecmtech.fr

ECM GREENTECH

Tel.: +33 (0)4 76 49 65 60
info-pv@ecmtech.fr

ECM USA, INC.

Tel.: +1 262 605 4810
info@ecm-usa.com

ECM (CHINA) CO. LTD.

Tel.: + 86 10 85802642/3 ext.101
contact.b@ecm-china.com

ECM FURNACE INDIA PVT. LTD.

Tel: +33 (0)4 76 49 65 60
info@ecmtech.fr

ECM KAZAKHSTAN. LLP.

Tel.: + 7 7172 990 440
info-pv@ecmtech.fr